## AMENDMENTS TO THE CLAIMS

This listing of claims replaces all prior versions, and listings, of claims in the application:

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- 1. (Canceled)
- 2. (Canceled)
- 3. (Canceled)
- 4. (Canceled)
- 5. (Currently amended) A mechanically actuated airtight device for a wafer carrier, the device comprising:

a cover, having a stem, a first face and a second face, and the cover being formed with at least one hole therethrough;

at least one sealing gasket, the sealing gasket being positioned above the hole of the cover, the sealing gasket having a base in a form of a wedged ramp, and the base having a through opening;

two linked plates, a first plate and a second plate, each of the linked plates keeping a distance from one another and having a first face, a second face wherein the first plate having a first and a second face, the second plate having a first and a second face, and each of the first plate and the second plate having a lug with a first side and a second side, the first side of the lug being provided with a protuberance—on—one side, and the first face of the first linked—plate being provided with at least one wedged ramp, and the wedged ramp of the first face of the first linked—plate having a slope equal to that of the wedged ramp of the base, such that the wedged ramp of the first face of the first linked—plate mates with—and the wedged ramp of the base—on a lock state mate each other along the slope surfaces;

a driving wheel, having a first face and a second face, the first face of the driving wheel being provided with stops and a first guiding groove, the first face of the driving wheel facing the second face of the <u>first linked-plate and the second face of the second plate</u>, the second face of the driving wheel being provided with a second guiding groove, wherein the driving wheel abuts the <u>lug of the lug of the first linked-plate and the lug of the second plate</u>, and the abutment allows <u>such that</u> the protuberance of the <u>first linked-plate and the protuberance of the second plate moves to move</u> along the first guiding groove and is limited by the stops; and

a bottom having a first face and a second face, the first face of the bottom being located beneath coupled to the second face of the driving wheel, and the bottom being engaged with the cover, wherein a circular rail is provided on the first face of the bottom and moves along the second guiding groove on the second face of the driving wheel;

wherein the <u>first plate and the second plate</u> two linked plates only move rightward and <u>leftward-linearly move inward toward the stem and outward away from the stem</u> by rotating the driving wheel such that the wedged ramp of the base and the wedged ramp of the first face of the first <u>linked-plate</u> seal or release the through opening.

- 6. (Canceled)
- 7. (Previously presented) A mechanically actuated airtight device for wafer carrier as set forth in claim 5, wherein the sealing gasket has a first face on which a rim is formed.
- 8. (Currently amended) A mechanically actuated airtight device for wafer carrier as set forth in claim 5, wherein at least one of the wedged ramp of the first face of the linked plate and the wedged ramp of the base is made of elastomeric material.